

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Koichiro TANAKA et al.)	New Applications
Based On: JP 2003-101312)	
Filed: April 4, 2003)	
For: LASER IRRADIATION METHOD,)	
LASER IRRADIATION APPARATUS)	
AND METHOD FOR)	
MANUFACTURING)	
SEMICONDUCTOR DEVICE)	

PRELIMINARY AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Drawings begin on page 2 of this paper and include an attached replacement sheet.

Remarks begin on page 3 of this paper.

Amendments to the Drawings:

The attached corrected drawing sheet includes changes to Fig. 1B to correct a typographical error. Specifically, the legend "1st pulse laser" was misspelled as "1st pulse lasre" and is corrected herewith.

Attachment: Replacement Sheet